

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Withdrawn) An organic thin film manufacturing method, comprising:

feeding an organic material in a vapor state into a line source that is positioned in a vacuum chamber where deposition occurs, wherein said organic material in a vapor state is fed from a material introducing part that is positioned outside said vacuum chamber where deposition occurs, and

forming a thin film of said organic material on at least one substrate disposed inside said vacuum chamber,

wherein the pressure inside said material introducing part is set independently of the pressure inside said vacuum chamber where deposition occurs, and wherein said material introducing part is exhausted through an exhauster that independent of the exhauster of said vacuum chamber.

2. (Withdrawn) The organic thin film manufacturing method according to claim 1, wherein said material introducing part comprises a crucible for holding said organic material, crucible fixing means for holding said crucible, and heating means for heating said crucible, and said organic material is vaporized by heating said crucible using said heating means.

3. (Withdrawn) The organic thin film manufacturing method according to claim 1, wherein said line source has a blocking plate for dispersing the vapor-state organic material that has been fed therein, and said blocking plate is temperature-regulated.

4. (Currently amended) An organic thin film manufacturing apparatus, comprising:

a vapor deposition apparatus comprising a line source positioned in a vacuum chamber where deposition occurs, said vacuum chamber being connected to a first exhauster, and

a material introducing part positioned outside of said vacuum chamber, in which pressure can be set independently of the pressure in said vacuum chamber, said material introducing part being connected to an a second exhauster that is independent to that of said vacuum chamber,

wherein a vapor-state organic material is fed into said line source from said material introducing part, to form a thin film of said organic material on at least one substrate disposed inside said vacuum chamber.

5. (Original) The organic thin film manufacturing apparatus according to claim 4, wherein said material introducing part comprises a crucible for holding said organic material, crucible fixing means for holding said crucible, and heating means for heating said crucible.

6. (Original) The organic thin film manufacturing apparatus according to claim 4, wherein said line source has a blocking plate for dispersing the vapor-state organic material that has been fed therein, and said blocking plate is temperature-regulated.

7. (Withdrawn – currently amended) An organic EL device manufacturing method, comprising:

~~forming a first electrode on at least one substrate;~~

forming an organic EL layer on said first electrode by feeding an organic material in a vapor state from a material introducing part positioned outside a vacuum chamber where deposition occurs into a line source in said vacuum chamber where deposition occurs, wherein the pressure in said material introducing part is set independently from that of said vacuum

chamber where deposition occurs and wherein said material introducing part is exhausted through an exhauster that is independent of said vacuum chamber where deposition occurs; and

~~forming a second electrode on said organic EL layer.~~

8. (Withdrawn) The organic EL device manufacturing method according to claim 7, wherein said material introducing part comprises a crucible for holding said organic material, crucible fixing means for holding said crucible, and heating means for heating said crucible, and said organic material is vaporized by heating said crucible using said heating means.

9. (Withdrawn) The organic EL device manufacturing method according to claim 7, wherein said line source has a blocking plate for dispersing the vapor-state organic material that has been fed therein, and said blocking plate is temperature-regulated.

10. (Currently amended) An organic EL device layer manufacturing apparatus, comprising[[:]]

~~means for forming a first electrode;~~

means for forming an organic EL layer; and

~~means for forming a second electrode;~~

wherein said means for forming an organic EL layer comprises a vapor deposition apparatus that has a line source positioned in a vacuum chamber where deposition occurs, and a material introducing part that is positioned outside said vacuum chamber of said vapor deposition apparatus, wherein said material introducing part and said vacuum chamber comprise separate means for setting the pressure in each of them independently and wherein

said material introducing part is exhausted through an exhauster that is independent of said vacuum chamber where deposition occurs,

wherein forming of said organic EL layer comprises feeding an organic material in a vapor state from said material introducing part into said line source to form said organic EL layer on at least one substrate disposed inside said vacuum chamber of said vapor deposition apparatus.

11. (Currently amended) The organic EL device layer manufacturing apparatus according to claim 10, wherein said material introducing part comprises a crucible for holding said organic material, crucible fixing means for holding said crucible, and heating means for heating said crucible.

12. (Currently amended) The organic EL device layer manufacturing apparatus according to claim 10, wherein said line source comprises a blocking plate for dispersing the vapor-state organic material that has been fed therein, and said blocking plate is temperature-regulated.

13. (New) The organic thin film manufacturing apparatus according to claim 6, wherein the blocking plate has a number of holes sufficient to form a uniform vapor stream within the source.

14. (New) The organic thin film manufacturing apparatus according to claim 13, wherein the holes are distributed over the whole of blocking plate.

15. (New) The organic thin film manufacturing apparatus according to claim 13, wherein the blocking plate has a large number of holes.

16. (New) The organic EL layer manufacturing apparatus according to claim 12, wherein the blocking plate has a number of holes sufficient to form a uniform vapor stream within the source.

17. (New) The organic thin film manufacturing apparatus according to claim 16, wherein the holes are distributed over the whole of blocking plate.

18. (New) The organic EL layer manufacturing apparatus according to claim 16, wherein the blocking plate has a large number of holes.